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MILITARY STANDARDIZATION HANDBOOK

OPTICAL DESIGN

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Optical Design
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1. This handbook was developed by the Department of Defense with the assistance of a leading optical manufacturer. Major contributions were made by persons who, by virtue of experience in their particular fields, are recognized as qualified authorities on the subject of optical design.

2. This publication was approved on 5 October 1962 for printing and inclusion in the military standardization handbook series.

3. This document provides engineering personnel with an introduction to optical theory, and treats to an advanced level the fundamentals and principles of optical design. It is expected that wide distribution of the methods of design and computation presented in this handbook will result in a more efficient and accurate method of complying with military optical requirements.

4. To aid in maintaining the intended status of this handbook as a source of prevailing information, readers are encouraged to report any errors and suggestions for changes and additions to the Standardization Division, Defense Supply Agency, Washington 25, D. C.

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REF AUTHOR

1. Dr. Robert E. Hopkins, University of Rochester
   Dr. Richard Hanau, University of Kentucky
2. Dr. Harold Osterberg, American Optical Company
3. Dr. Oscar W. Richards, American Optical Company
4. Dr. Robert E. Hopkins, University of Rochester
5. Mr. A. J. Kavanagh, American Optical Company
6. Dr. Ralph Wight, Photronics Corporation
7. Dr. Seymour Rosin, Scanoptic, Incorporated
8. Dr. Philip Baumeister, University of Rochester
9. Mr. Alva Bennett, American Optical Company